

ABSTRACT

A method for detecting a wafer shipping box includes a detecting step
5 and a determining step. The detecting step includes: using detection modules to
detect a predetermined position, and using a processing module to convert the
detection results from the detection modules into detection values; wherein
detection ranges of two adjacent ones of the detection modules are partially
overlapped. The determining step includes: determining whether a
10 predetermined position of the wafer shipping box is provided with an auxiliary
member by the processing module. When more than half of the detection
values fall in a first predetermined value range, the predetermined position of
the wafer shipping box is determined to be provided with the auxiliary member;
when more than half of the detection values fall in a second predetermined
15 value range, the predetermined position of the wafer shipping box is determined
to not be provided with the auxiliary member.

FIG. 1